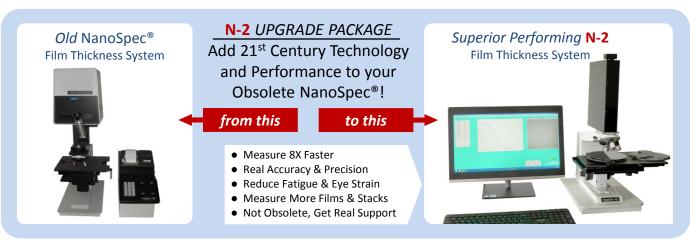




Introducing... the N-2







Description

The original equipment manufacturer *no longer supports* its older **NanoSpecs** leaving customers searching for third party service when failures occur. In addition, these mechanical spectrophotometers with their simplistic *film-approximations* are not suited for today's manufacturing tolerances. An *upgrade path is now available* for these under-performing and unsupported film thickness measurement systems.

Breathe new life into your *obsolete* **NanoSpec 0174, 0180, 0181, 200** or **210** with the **N-2** conversion. The old mechanical spectrophotometer is replaced with a modern solid-state version, integrated long-life illumination system and a digital imaging system. A Windows 8 PC equipped with sophisticated film metrology algorithms and software replaces the 1970's computer-architecture and firmware. The **N-2** conversion transforms the dying **NanoSpec** into a useful asset that will provide additional years of service with performance beyond the OEM's original intent.

Additional Features & Benefits

- Affordability allows funding from maintenance budgets.
- Classic NanoSpec gross measurement errors (a.k.a. order jumping) are eliminated with modern technology.
- Digital imaging displays measurement site on FPD eliminating eye-strain commonly associated with the old NanoSpec monocular.
- Sophisticated algorithms expand film/stack library.
- Eliminating classic NanoSpec gain-pot and wavelength adjustments improves performance and simplifies operation.
- Reflectance vs wavelength is graphically displayed with data modelling fit curve.
- FPD simultaneously displays active measurements, spectral curves, video image of measurement target and statistics.

Specifications

Thickness Range with 10X Lens:

• Thickness Range with optional 4X Lens:

• Measurement Time:

Measurement Spot Size Using 10X:

• Short-Term Repeatability¹:

• Long-Term Repeatability²:

• Lamp Life:

• Wavelength Range:

30nm to 25 μm

30nm to 70 μm

< 1 second

< 1 Second

10 μm

1 nm

1 nm

5,000 hours

450 to 850 nm

Notes: oxide on silicon material stack used to establish measurement specifications. 1) 1 sigma for 20 fixed-point, consecutive measurements of 10 μm oxide on Si. 2) 1 sigma of daily average of short term repeatability over 30 days.

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